Preliminary programme WELT-PP4, November 22nd and 23rd, 2001

Thursday, November 22nd

10.30	**Coffee/Tea in the Foyer**	
11:15	**Welcome**	
Session 1	(Conference room 4)	
11.20-12.00	O1	**Supersonic Planar Plasma Expansions as a Tool for High Resolution Spectroscopy** H. Linnartz (University of Basel)
12.00-12.25	O2	**Correlation between the plasma composition and the growth rate of a-C:H films** J. Benedikt (Eindhoven University of Technology)
12.30	**Lunch in the "Grote Eetzaal"**	
Session 2	(Conference room 4)	
14.00-14.25	O3	**Particles dynamics in capacitively coupled rf dusty plasma** R.P. Dahiya (Eindhoven University of Technology)
14.25-14.50	O4	**2D voids in argon, oxygen and argon-oxygen dusty plasmas** G.V. Paeva (Eindhoven University of Technology)
14.50-15.15	O5	**Treatment of Bone Tissue using an Inductively Coupled Plasma** C.Y.M. Maurice (Eindhoven University of Technology)
15.15	**Coffee/Tea in the Foyer**	
Session 3	(Conference room 4)	
16.00-16.40	O6	**Spontaneous Branching of Anode-Directed Streamers** Ute Ebert (CWI Amsterdam)
16.40-17.05	O7	**A Novel Electrical Circuit for Large Pulsed Power Generation** K. Yan (Eindhoven University of Technology)
17.05-17.30	O8	**Electrical and optical investigations on barrier discharges in coplanar arrangements** L. Hulka (Eindhoven University of Technology)
18.00	**Dinner in the "Grote Eetzaal"**	
20.00	**Poster session** (Conference room 3 (Fabritius room)). Posters can be posted from 14:00 and remain up until Friday. During the poster session the bar will be open. **At approx. 21.00 the Farmers cellar bar opens until 24.00.**	

Friday, November 23rd

08.00	**Breakfast in the “Grote Eetzaal”**	
Session 4	(Conference room 4)	
09.00-09.25	O9	**Thomson scattering on a low pressure, inductively coupled gas discharge lamp** M.J. van de Sande (Eindhoven University of Technology)
09.25-09.50	O10	**Continuum Radiation in High Pressure Lamps** K.T.A.L. Burm (Philips Research Laboratories Aachen)
09.50-10.15	O11	**Mercury-Free High Pressure Discharge Lamps** M. Born (Philips Research Laboratories Aachen)
10.15		**Coffee/Tea in the Foyer**
Session 5	(Conference room 4)	
10.45-11.25	O12	**Development of a Thomson scattering system for micro-discharge plasmas** M. Bowden (Eindhoven University of Technology)
11.25-11.50	O13	**Expanding thermal plasma deposition of silicon dioxide-like films for microelectronic devices** M. Creatore (Eindhoven University of Technology)
11.50-12.15	O14	**In-situ FTIR measurements in a HMDSO plasma discharge** L. George-Felix (Bergische Universität GH Wuppertal)
12.30	**Lunch in the “Grote Eetzaal”**	
Session 6	(Conference room 4)	
14.00-14.25	O15	**High rate depotion of silicon nitride for multicrystalline silicon solar cells using an N_2/SiH_4 and NH_3/SiH_4 expanding thermal plasma** J. Hong (Eindhoven University of Technology)
14.25-14.50	O16	**Investigation on an Inductively Coupled Plasma in Hydrogen** U. Czarnetzki (Universität Essen)
14.50-15.15	O17	**Atmospheric pressure hollow cathode jet matrix plasma source** A. Ignatkov (Bergische Universität GH Wuppertal)
15.15	**Closure of the workshop, drinks in the Foyer**